



2822
PATENT
81877.0007

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Norikazu MIZUNO et al

Serial No: 09/670,917

Filed: September 29, 2000

For: SEMICONDUCTOR DEVICE
MANUFACTURING METHOD AND
APPARATUS FOR REMOVING SILICON
NITRIDE FORMED IN A REACTION
CONTAINER (AS AMENDED)

Art Unit: 2822

Examiner: M. R. Guerrero

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to:
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450, on
December 4, 2003.
Date of Deposit
Anthony J. Orler, Reg. No. 41,232
Signature Date 12/04/03

PETITION FOR EXTENSION OF TIME

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In accordance with 37 C.F.R. 1.136, Applicant respectfully petitions the Commissioner for a three-month extension of time extending to December 4, 2003, the period for response to the Office Action dated June 4, 2003. Please charge the fee of \$950 for this extension to Deposit Account No. 50-1314. The responsive paper(s) are attached.

Please charge any insufficiency or credit any overpayment to Deposit Account No. 50-1314. A copy of this petition is enclosed.

12/10/2003 JBALIMH 00000068 501314 09670917

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Date: December 4, 2003

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Respectfully submitted,

HOGAN & HARTSON LLP.

By:

Anthony J. Orler
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Attorney for Applicant(s)

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